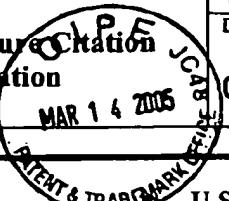


PTO-1449 Information Disclosure & Citation In an Application		Application No. 10/649,925	Applicant(s) Kovacevic et al.	
		Docket Number 021791.0109	Group Art Unit 2125	Filing Date 08/25/2003

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CK A	6,122,564	09/19/2000	Koch et al.	700	123	06/30/1998
CK B	6,188,041	02/13/2001	Kim et al.	219	121.63	11/13/1998
CK C	6,311,099	10/30/2001	Jasper et al.	700	166	10/15/1998
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CK E	6,459,951	10/01/2002	Griffith L.	700	166	09/10/1999
CK F	6,526,327	02/25/2003	Kar et al.	700	119	12/07/2000
CK G	6,638,787	10/28/2003	Buchin et al.	438	75	12/04/2001
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I						
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	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES NO
CK O		07/06/1999	Japan	B23K	26/02	XX
CK P	WO 03/070414 A1	08/28/2003	PCT	B23K	26/03	XX
Q						

OTHER DOCUMENTS (Including Author, Title, Source, and Pertinent Pages)**DATE**

R

S

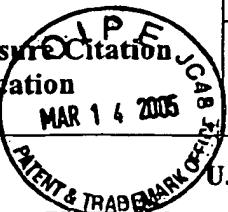
T

EXAMINER*Chuck Kovacevic***DATE CONSIDERED***3/28/05*

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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PTO-1449 Information Disclosure Citation In an Application		Application No. 10/649,925	Applicant(s) Kovacevic et al.	
		Docket Number 021791.0109	Group Art Unit 2125	Filing Date Aug. 25, 2003



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CK	A	6,391,251	05/21/02	Keicher et al.	419	7	05/09/2000
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CK	E B. Grünenwald et al., "New Technological Developments in Laser Cladding", Proceedings of the International Congress on Applications of Lasers and Electro-Optics (ICALEO 1993), pp. 934-944.	1993
CK	F Lii et al., "Sensing, Modelling and Closed Loop Control of Powder Feeder for Laser Surface Modification", Proceeding of the International Congress on Applications of Lasers and Electro-Optics (ICALEO 1993), pp. 965-974.	1993
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CK	L Dongming Hu et al., "Sensing, Modeling and Control for Laser-Based Additive Manufacture", International Journal of Machine Tools & Manufacture 43 (2003) pp. 51-60	2003
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EXAMINER <i>Chait Kovacevic</i>	DATE CONSIDERED <i>3/28/05</i>
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